

PATENT 8074-1143

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Koichi NANIWAE

Conf. unknown

Application No. 10/573,492

Group unknown

Filed March 24, 2006

Examiner unknown

METHOD OF CLEANING TREATMENT AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 June 27, 2006

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the accompanying document, a copy of which is attached to this statement, is made of record on the enclosed sheet.

A concise explanation of the relevance of this item is that this reference is discussed on pages 3 and 4 of the present specification.

Respectfully submitted,

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* Abstract provided for the Examiner's convenience